

OVEN DOPE1-DOPE4:

Configuration:

- Process type: POCL3 DOPE
- Wafer size: configured for 6 inch
- Gas configuration:

Stocker

Stage

1: 2: 3:

4: 5: 6:

7: 8:

IOPort

JOB
Status

Temperature

TOP 800.0

T-CTR 800.1

CTR 800.1

B-CTR 800.0

BOTTOM 800.1

Boat
Elevator

Gas

Pressure Torr

Recipe Detail

DOPE12

Boat Detail

Process Status

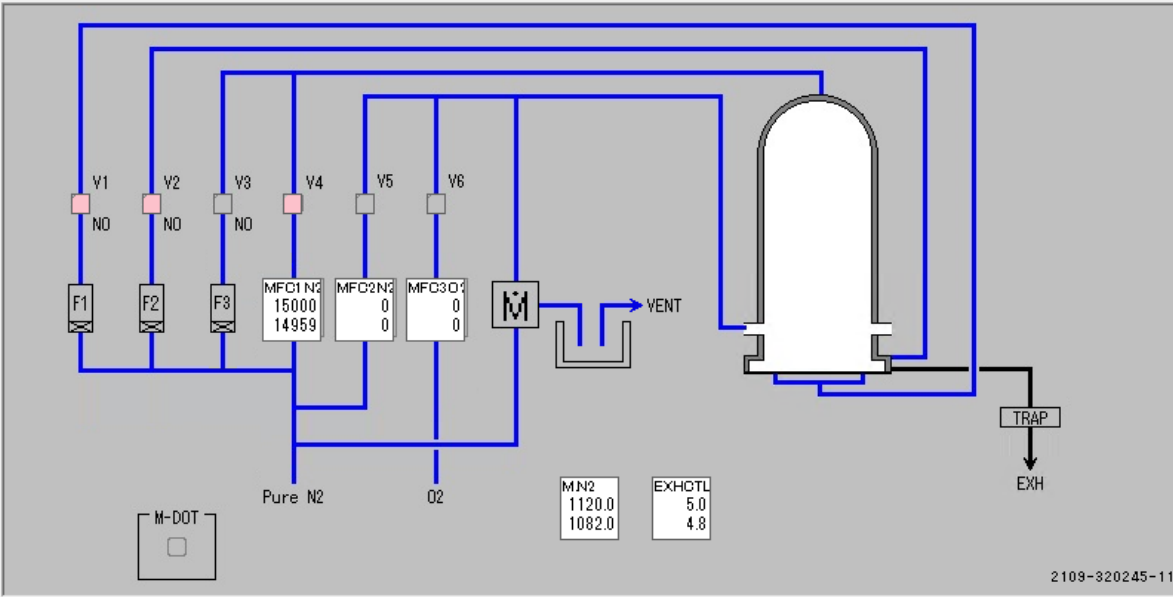
STANDBY **READY** RUN END ABORT

HOLD ON ONLINE ABORTEND

Recipe Step

Remain Time

Start Time Finish Time Processing



- Gas leak detection:
No detection units in the tool, only house detection
- Wafer handler: TBAWL
- TUBE controller: M3100
- Power supply: Single phase 220V / 3 phase 400V
- FOUP: ?
- Heater type: ?
- Notch aligner: NO
- MFC: STEC/BROOKS
Schumacher MDOT controller for POCL3
- RCU: ?
- Vintage: 1995
- OS Type: M3100
- SW Version: EPROM